

2011 International Meeting for Future of Electron Devices

(IMFEDK 2011)

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The Conference Theme

“Nanotechnology and Its Impact on Electron Devices”

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T. Takamoto (Sharp Corp.)

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(¹University of Hyogo, ²Kansai University, ³Hiroshima University)

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- B-4** (p.46) Thin Film Transistors and Photo Diodes Fabricated on Double-Layered Polycrystalline Silicon Films Formed by Green Laser

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K. Yamasaki¹, E. Machida¹, M. Horita^{1,2}, Y. Ishikawa^{1,2}, Y.
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Awards & Closing Remark

17:30-17:40 Award Presentation: Y. Ohmura (Kansai University)

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